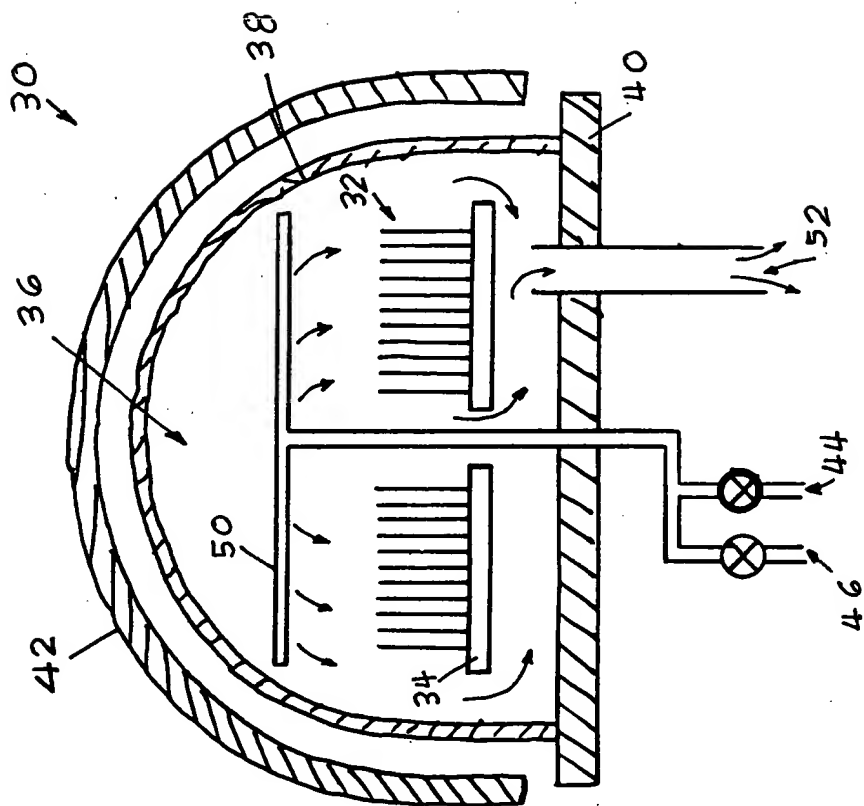


FIG. 1

PRIOR ART



PRIOR ART

FIG. 2

FIG. 3

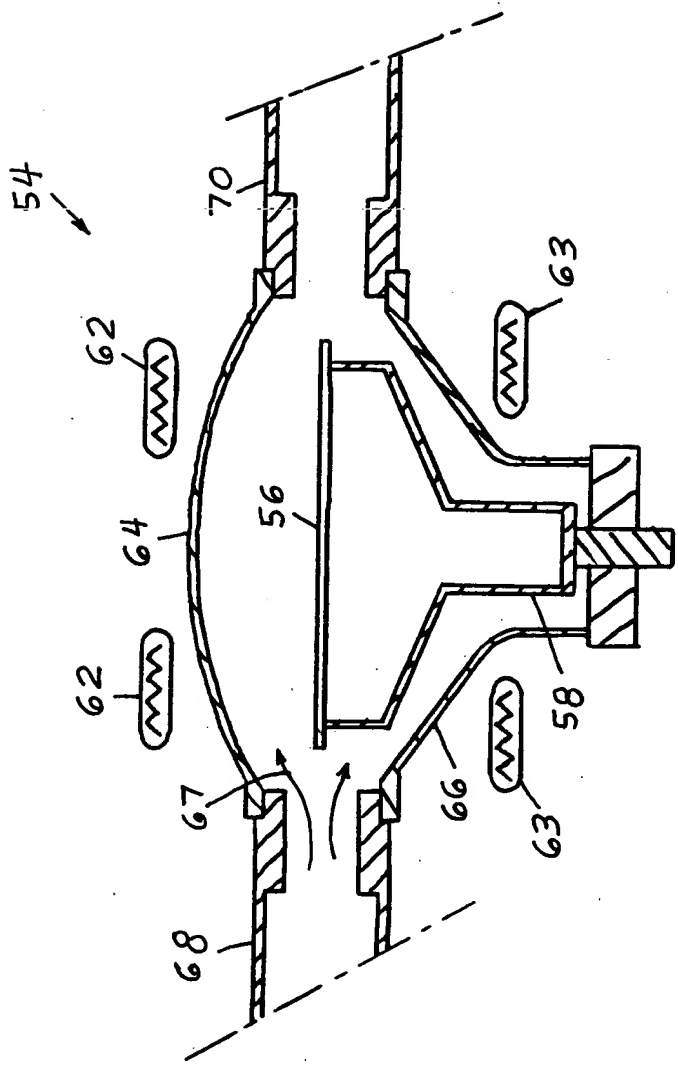


FIG. 3

PRIOR ART

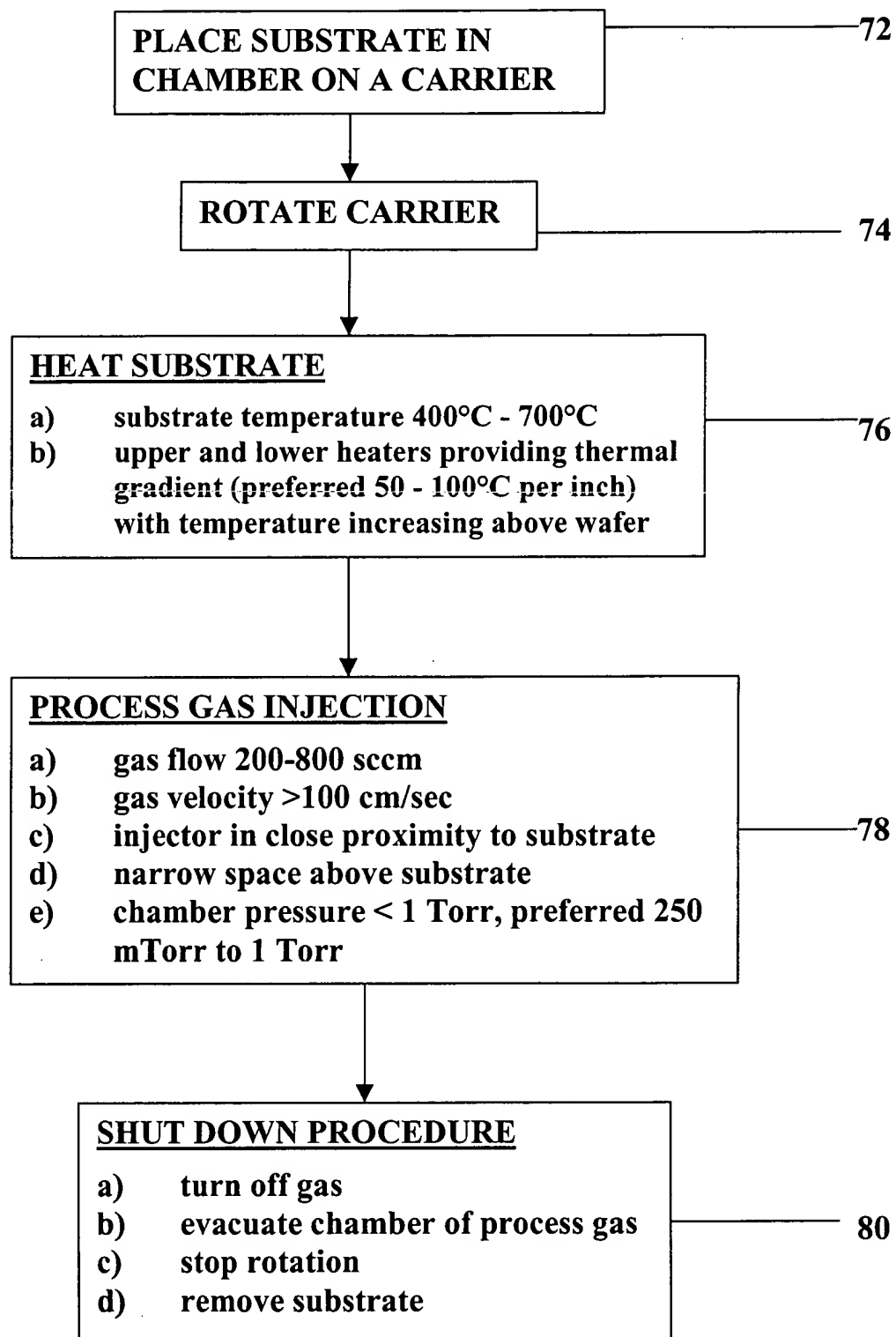


FIG. 4

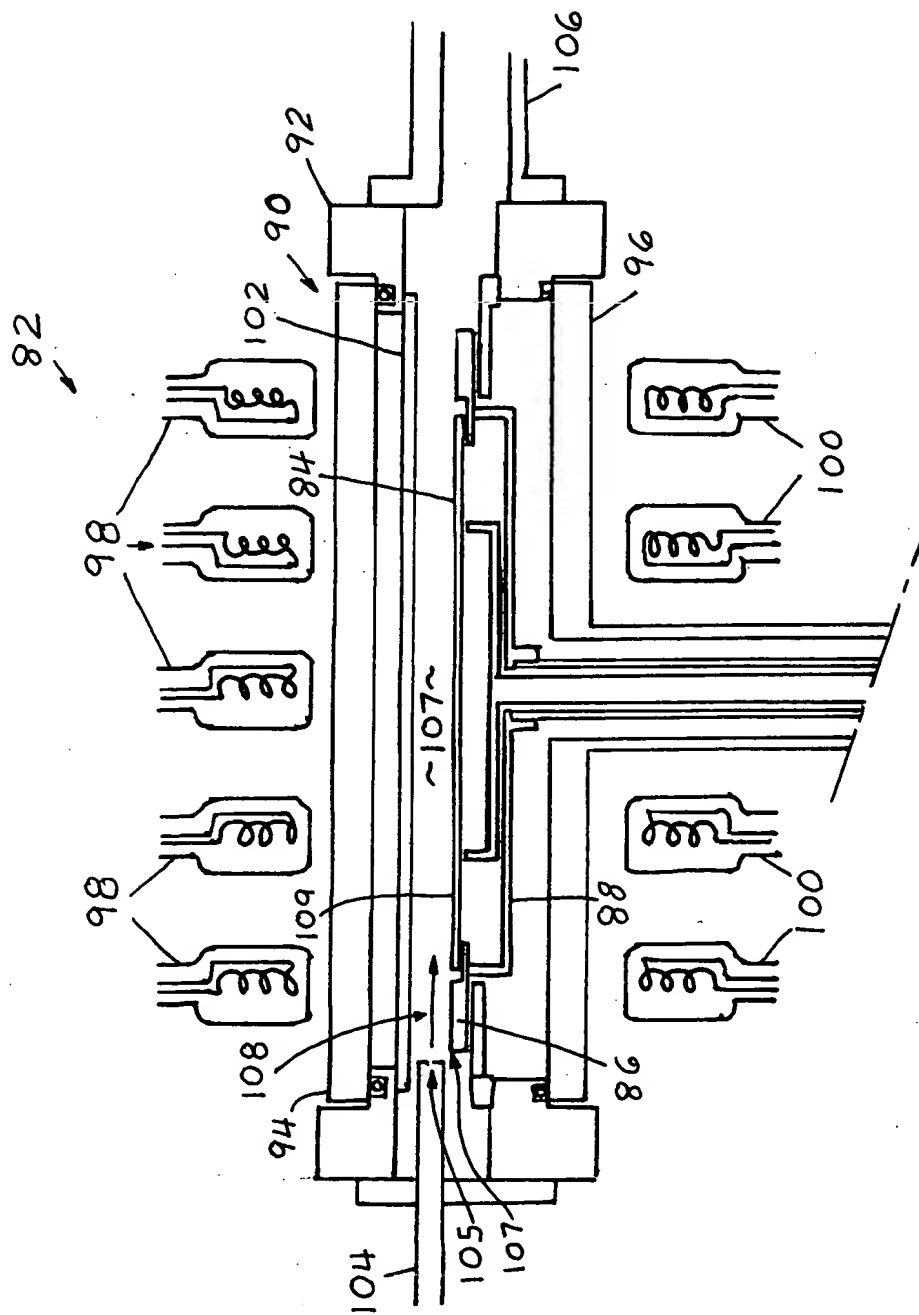


FIG 5

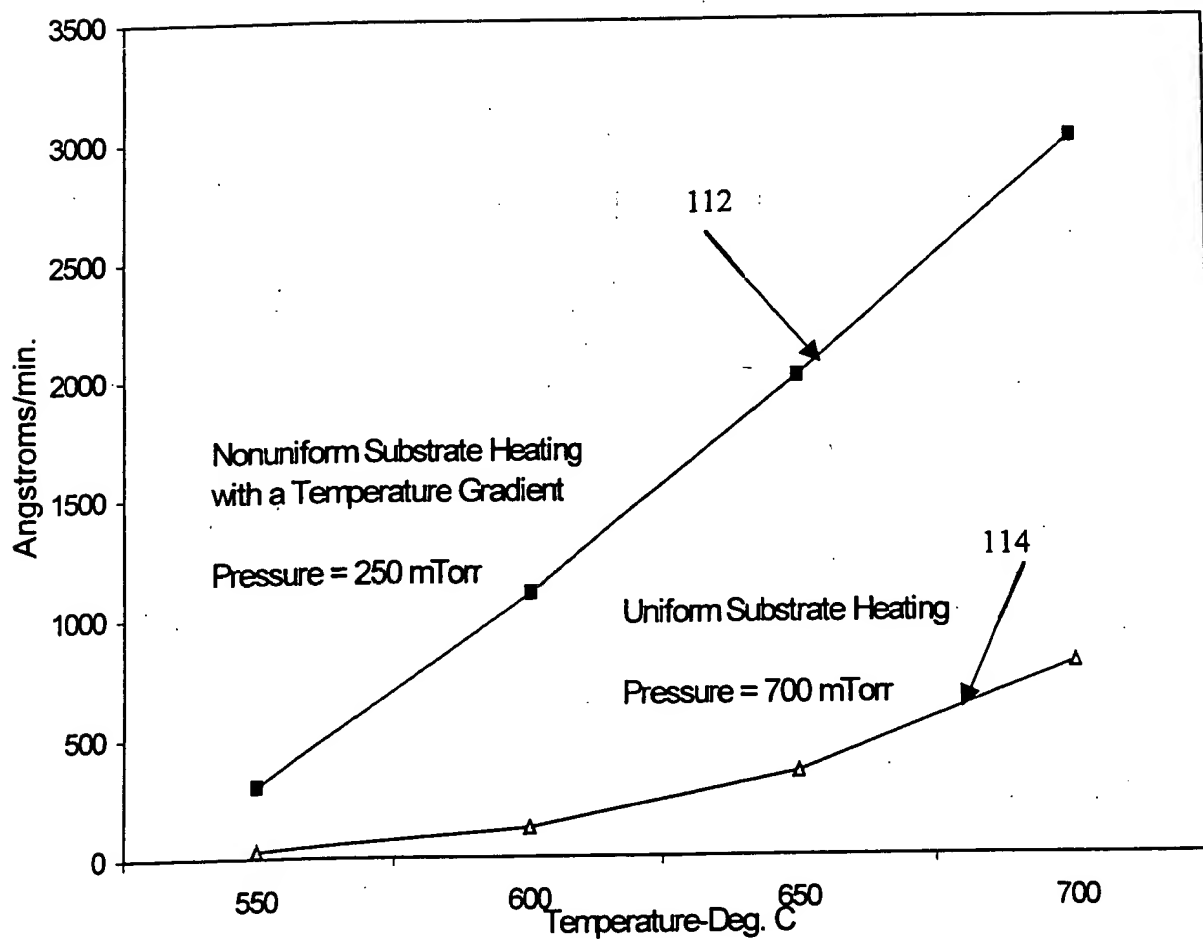
[illegible]

Figure 6

Silicon Deposition Rate vs Silane Flow
with Non-uniform Substrate Heating

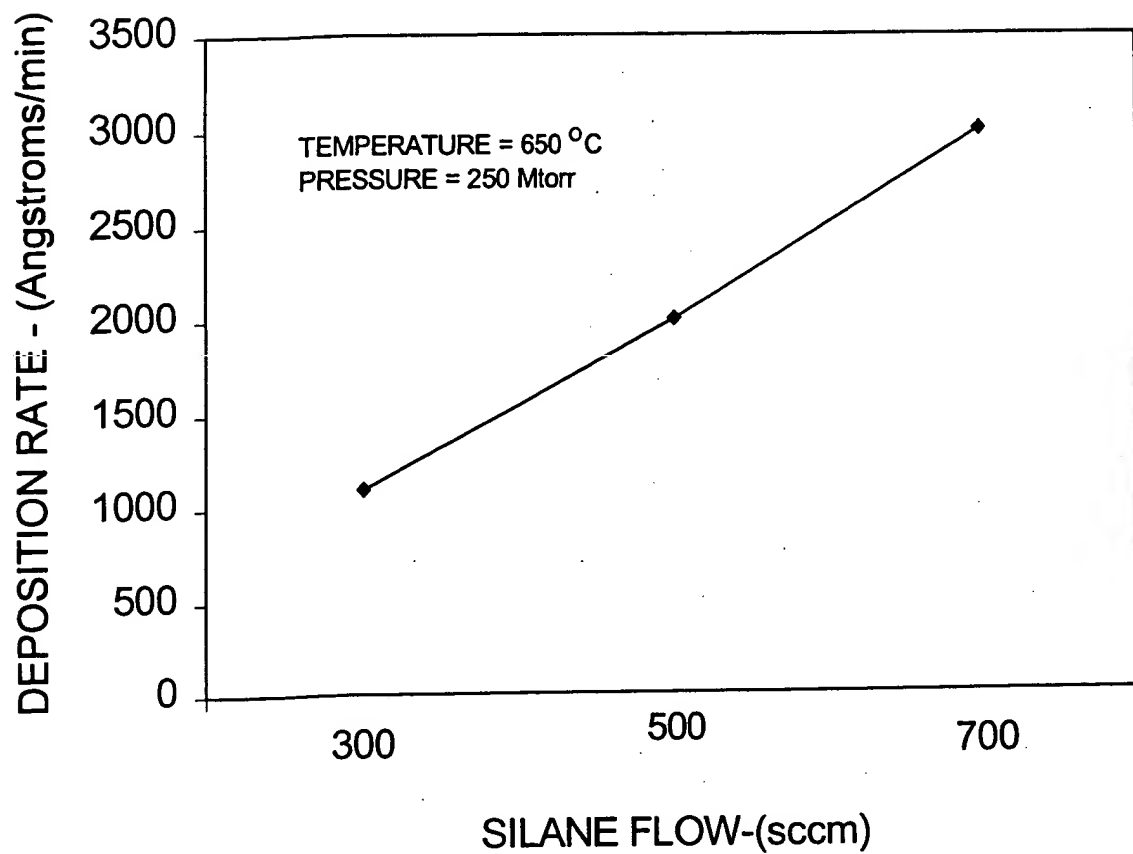


Figure 7

Silicon Nitride Deposition Rate versus Silane Flow

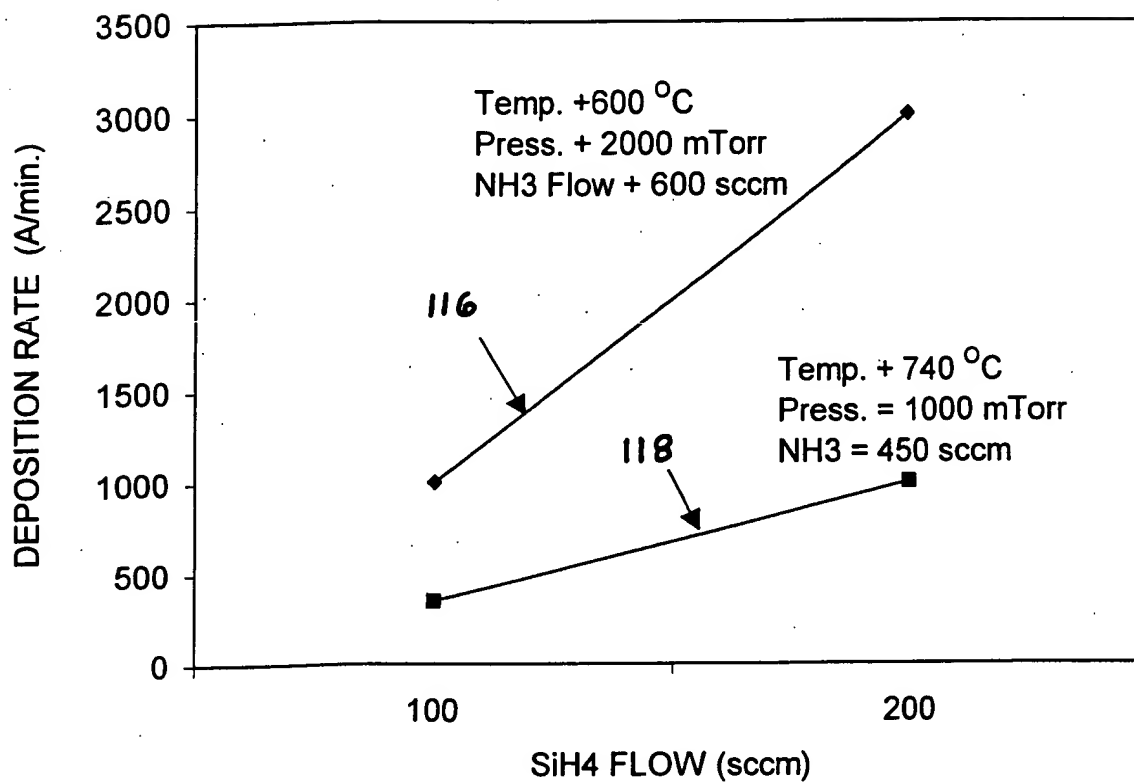


Figure 8

Silicon Nitride Deposition Rate versus Pressure

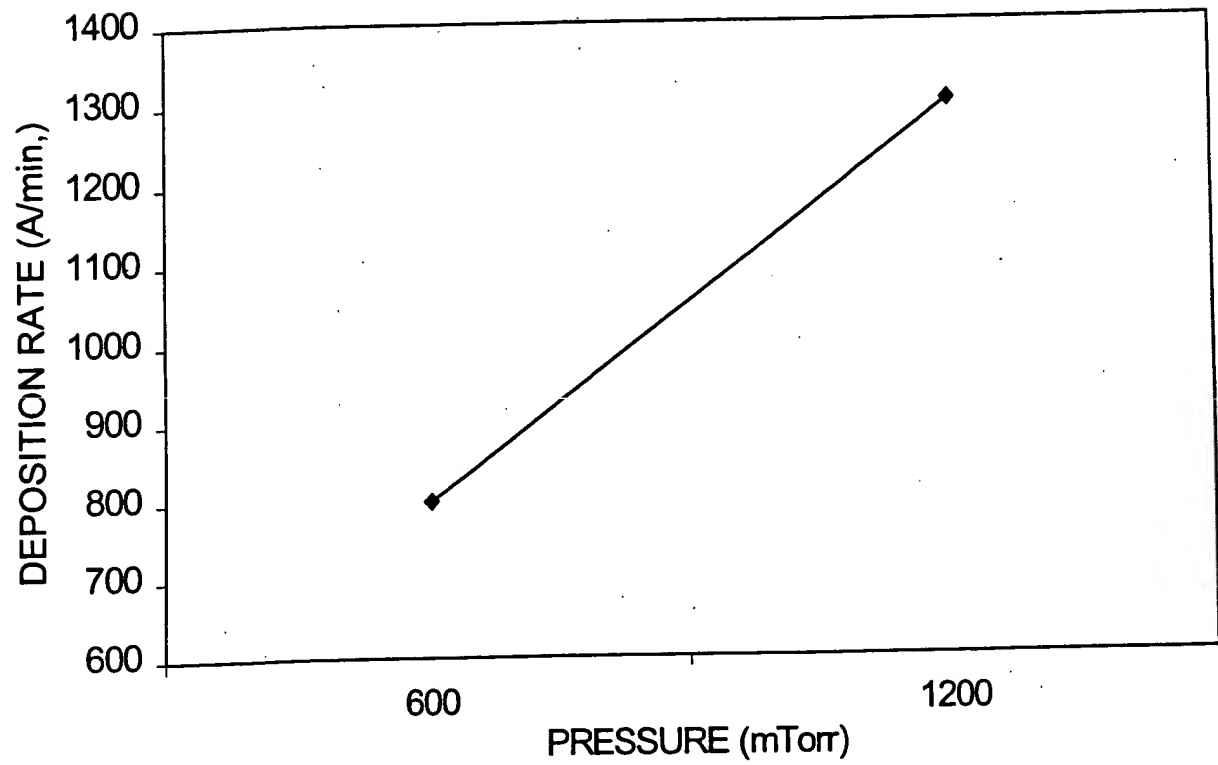


Figure 9